

SHEET 1 of 2

INFORMATION DISCLOSURE CITATION PTO-1449		Atty. Docket No. NTI-022	Serial No. 10/003,358			
		Applicant CHANG, Fang-Cheng				
		Filing Date 11/14/2001	Group 244 2825			
U.S. PATENT DOCUMENTS						
EXAMINER'S INITIALS	PATENT NO.	DATE	NAME	CLASS	SUBCLASS	FILING DATE
<i>JSP</i>	5,282,140	1/25/1994	Tazawa, et al.	364	468	6/24/1992
	6,130,750	10/10/2000	Ausschnitz, et al.	356	401	8/28/1997
	6,229,025 B1	5/1/2001	Hoshino	430	296	9/22/1998
	6,339,836 B1	1/13/2002	Eisenhofer, et al.	716	5	8/24/1998
<i>JSP</i>	6,346,426 B1	2/12/2002	Toprac, et al.	438	8	11/17/2000

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EXAMINER:

James S. P. T. S.
 EXAMINER: Initial if reference considered, whether or not citation is in conformance with
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Date Considered:

8-8-05

NTI Use Only: 749:236:1

SHEET 2 of 2

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		Applicant CHANG, Fang-Cheng	
		Filing Date 11/14/2001	Group 246 2825
OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)			
EXAMINER'S INITIALS	CITATION		
<i>Jes</i>	Lin, B.J., et al., "Single-Level Electric Testsites for Phase-Shifting Masks", SPIE, Vol. 1673, pp. 221-228, March 9-11, 1992.		
	Cobb, N., "Fast Optical and Process Proximity Correction Algorithms for Integrated Circuit Manufacturing", Dissertation, University of California at Berkeley, UMI Microform 9902038 (139 pages).		
	Uhrig, W., et al., "Model of an Instrumented Opto-Electronic Transmission System in HDL-A and VHDL-AMS", SPIE, Vol. 3893, pp. 137-146, October 1999.		
<i>Jes</i>	Gronik, Y., et al., "Sub-Resolution Process Windows And Yield Estimation Technique Based On Detailed Full-Chip CD Simulation", SPIE, Vol. 4182, pp. 333-341 (2000).		

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EXAMINER:

Jam San Lin

Date Considered:

8-8-05

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